



41

2877

XA-9387
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183 /

Group Art Unit: 2877

Filed: November 17, 2000

Examiner: R. Punnoose

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING THE SAME MEASURING METHOD, AND EXPOSURE METHOD

* * *

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed July 15, 2003, and to the requirement for restriction therein, Applicant elects I (Claims 1-9, 27-30, 33 and 35), reserving the right to file one or more divisional applications regarding the non-elected inventions.

The Commissioner is hereby authorized to charge to Deposit Account No. 50-1165 any fees under 37 C.F.R. §§1.16 and 1.17 which may be required by this paper, and to credit any overpayment to that Account. If any extension of time

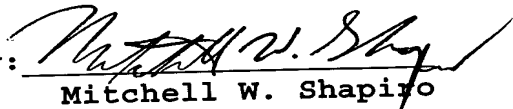
RECEIVED
AUG - 8 2003
TECHNOLOGY CENTER 2800

is required in connection with the filing of this paper and
has not been requested separately, then such extension is
hereby requested.

Respectfully submitted,

MWS:jab

Miles & Stockbridge P.C.
1751 Pinnacle Drive, Suite 500
McLean, Virginia 22102-3833
(703) 903-9000

By: 
Mitchell W. Shapiro
Reg. No. 31,568

August 6, 2003